Supplementary Information

Direct Patterning of Liquid Materials on Flat and Curved Substrates Using Flexible Molds with Through-hole and Post Arrays

Youngchul Chae¹, Juyeol Bae², and Taesung Kim^{1,3}*

¹Department of Mechanical Engineering, Ulsan National Institute of Science and Technology (UNIST), 50 UNIST-gil, Ulsan 44919, Republic of Korea.
²School of Mechanical Engineering, Chonnam National University, 77 Yongbong-ro, Buk-gu, Gwangju 61186, Republic of Korea.
³Department of Biomedical Engineering, Ulsan National Institute of Science and Technology (UNIST), 50 UNIST-gil, Ulsan 44919, Republic of Korea.

*Correspondence

Taesung Kim Department of Mechanical Engineering Ulsan National Institute of Science and Technology (UNIST) 50 UNIST-gil, Ulsan 44919, Republic of Korea E-mail: tskim@unist.ac.kr Tel: +82-52-217-2313 Fax: +82-52-217-2409

Supplementary Figures



Figure S1. Fabrication process of the microfluidic platform featuring through-hole and post arrays. (a) Schematic of the photolithography process used to fabricate the SU-8 master mold and the subsequent soft lithography process for producing a PDMS mold. (b) Schematic of the fabrication of an OSTEMER membrane with through-hole and post arrays using the PDMS mold.



Figure S2. Characterization of defects in oil films patterned by varying the parameters of the square array of through-holes and posts. The diameter of the posts is d_p , and the distance between posts is l. The images marked in red dashed rectangles correspond to the case shown in Fig. 4c.



Figure S3. Characterization of defects in oil films patterned by varying the parameters of the hexagonal array of through-holes and posts. The diameter of the posts is d_p , and the distance between posts is l. The images marked in red rectangles correspond to the case shown in Fig. 4f.

- End of document -